Toward strain control of magnetism in few-layer CrI₃



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Nanoscience & Engineering

Undergrad. School / Major: Presbyterian College / Physics

Microelectronics

Background/Relevance

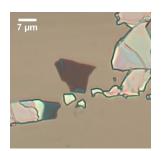
- The discovery of graphene ignited research into atomically thin materials, which can be manipulated to create new quantum devices dependent on the thickness of the materials
- Crl₃ is a known monolayer ferromagnet that can be cleaved into atomically thin layers for use in quantum devices
- It is predicted that biaxial compressive strain of CrI₃ will result in the formation of a quantum spin liquid, which is useful for quantum computing

Innovation

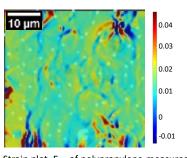
 Biaxial strain of few-layer Crl₃ will be used to tune its Curie temperature

Key Results

- The thickness of few-layer CrI₃ flakes was measured using optical contrast
- Biaxial strain of polypropylene substrates was measured using digital image correlation



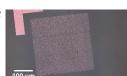
 Few-layer Crl₃ flake on a silicon substrate



- Strain plot, E_{xx}, of polypropylene measured using digital image correlation

Approach

- Create a polypropylene substrate with a speckle pattern using electron beam lithography
- Exfoliate thin flakes of CrI₃ onto a silicon substrate
- Use optical contrast techniques to measure the thickness of exfoliated layers
- Transfer few-layer Crl₃ onto a polypropylene substrate to apply compressive biaxial strain
- Future work will use an optical cryostat to measure the Kerr rotation of few-layer Crl₃ to determine the Curie temperature



- Speckle pattern on a polypropylene substrate



 Speckle pattern at a higher magnification

Conclusions

- The thickness of few-layer Crl₃ can be measured using optical contrast
- The biaxial strain of polypropylene can be quantified using digital image correlation
- Crl₃ flakes can be transferred from a silicon substrate onto a polypropylene substrate for compressive biaxial strain

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